

Docket No. 287990US2PCT



**MAIL STOP PCT**

*IFW*

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN RE APPLICATION OF: Jean-Charles GUIBERT

SERIAL NO: 10/572,353

GAU:

FILED: March 16, 2006

EXAMINER:

FOR: MICROLITHOGRAPHY METHOD USING A MASK WITH CURVED SURFACE

**INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97**

COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

SIR:

Applicant(s) wish to disclose the following information.

**REFERENCES**

- ☒ The applicant(s) wish to make of record the references listed on the attached form PTO-1449. Copies of the listed references are attached, where required, as are either statements of relevancy or any readily available English translations of pertinent portions of any non-English language references.
- ☐ A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

**RELATED CASES**

- ☐ Attached is a list of applicant's pending application(s), published application(s) or issued patent(s) which may be related to the present application. In accordance with the waiver of 37 CFR 1.98 dated September 21, 2004, copies of the cited pending applications are not provided. Cited published and/or issued patents, if any, are listed on the attached PTO form 1449.
- ☐ A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

**CERTIFICATION**

- ☐ Each item of information contained in this information disclosure statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.
- ☐ No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

**DEPOSIT ACCOUNT**

- ☒ Please charge any additional fees for the papers being filed herewith and for which no check or credit card payment is enclosed herewith, or credit any overpayment to deposit account number 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

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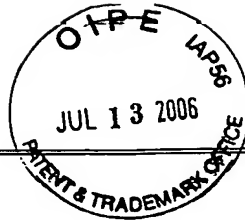
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Form PTO 1449  
(Modified)U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEATTY DOCKET NO.  
287990US2PCTSERIAL NO.  
10/572,353

## LIST OF REFERENCES CITED BY APPLICANT

APPLICANT

Jean-Charles GUIBERT

FILING DATE

March 16, 2006

GROUP

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA	2003/0104287	6/5/2003	YUASA, Mitsuhiro			
	AB	6 416 908	7/9/2002	KLOSNER, Marc A. et al.			
	AC	6 375 870	4/23/2002	VISOVSKY, Nick J. et al.			
	AD	5 281 511	1/25/1994	GERHARDT, Joergen			
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
	AO	199 13 683	11/25/1999	DE(equivalent of US 6 455 429)		NO
	AP	0 845 710	6/3/1998	EP(with English abstract)		NO
	AQ					
	AR					
	AS					
	AT					

## OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

	AU	RUCHHOEFT, P. et al., "Patterning curved surfaces: Template generation by ion beam proximity lithography and relief transfer by step and flash imprint lithography", Journal of Vacuum Science and Technology, Vol. 17, No. 6, Pages 2965-2969, 1999.				
	AV	ROGERS, J.A. et al., "Printing, molding, and near-field photolithographic methods for patterning organic lasers, smart pixels and simple circuits", Synthetic Metals, Vol. 115, No. 1-3, Pages 5-11, 2000.				
	AW	ROOS, Nils et al., "Nanoimprint Lithography with a Commercial 4 Inch Bond System for Hot Embossing ", Proceedings of The SPIE, Vol. 4343, Pages 427-435, 2001.				
	AX	CHOU, Stephen Y. et al., "Imprint of sub-25 nm Vias and trenches in polymers", Appl. Phys. Lett. Vol. 67, No. 21, Pages 3114-3116, 20 November 1995.				
	AY	TAN, Hua et al., "Roller nanoimprint lithography", J. Vac. Sci. Technol. Vol. 16, No. 6, Pages 3926-3928, 1998.				
	AZ	GUIBERT, Jean-Charles, "Nanotechnologies and nanolithography in Europe", Pages xxi-xxx.				<input type="checkbox"/> Additional References sheet(s) attached

Examiner

Date Considered

\*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

U.S. PCT Application Serial No: 10/572,353

Filed: March 16, 2006

Jean-Charles GUIBERT

Docket No. 287990 US



#### STATEMENT OF RELEVANCY

- 1) References AA - AD, AO - AP & AU - AW have been cited in the International Search Report. A copy of these references is being submitted herewith.
- 2) References            have been cited in the corresponding            Search Report. A copy of these references is being submitted herewith.
- 3) References AX & AY are discussed in the specification. A copy of these references is being submitted herewith.
- 4) Reference AZ is additional prior art known to Applicant. A copy of this reference is being submitted herewith.